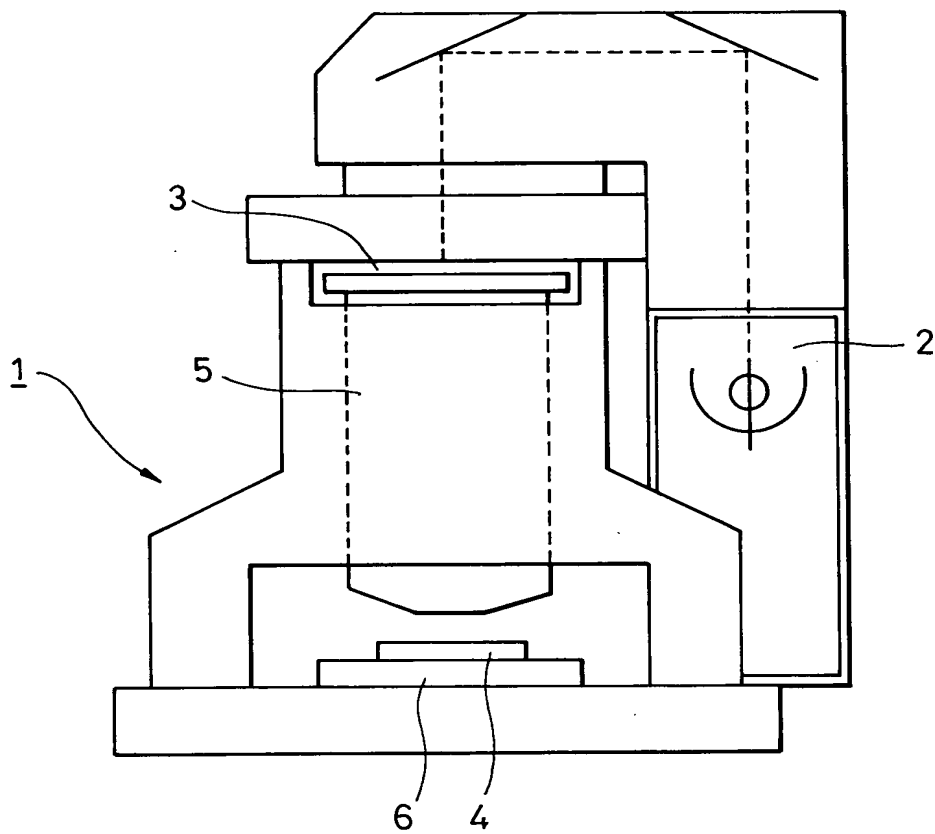
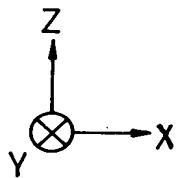
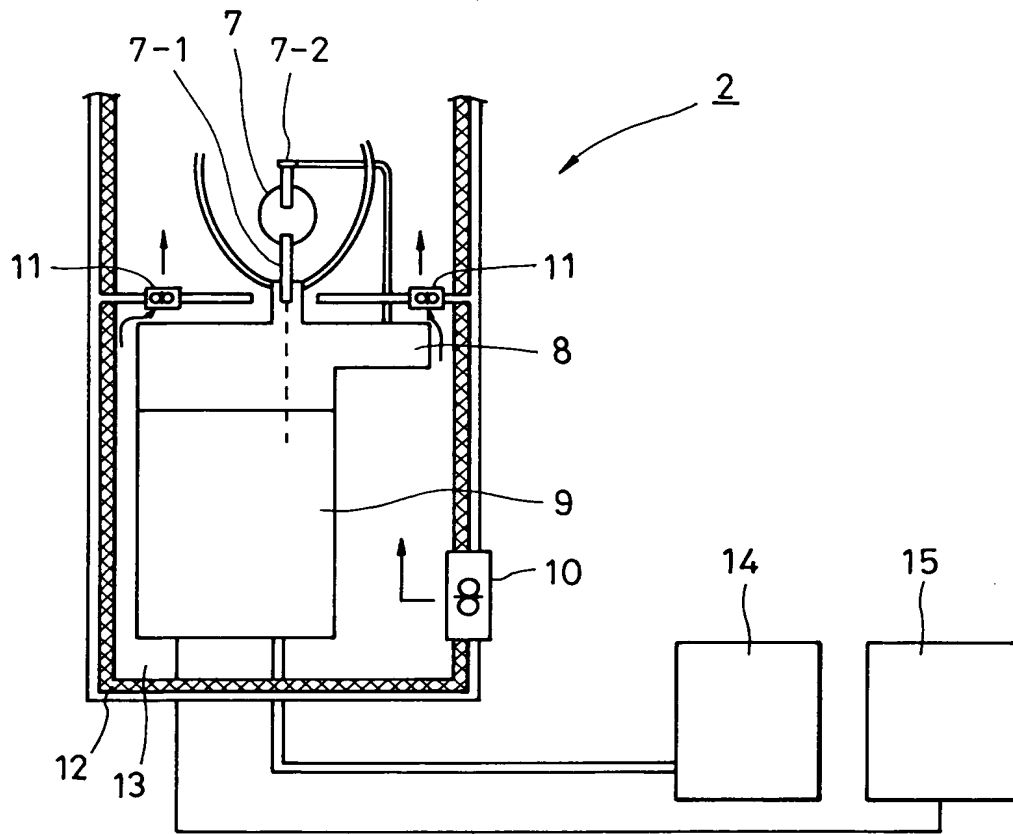


FIG. 1



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FIG. 2



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FIG. 3

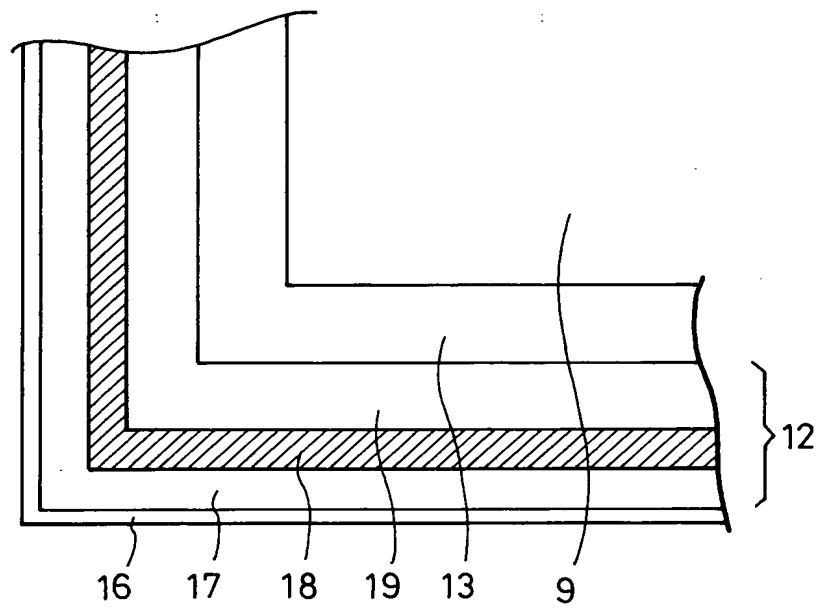


FIG. 4

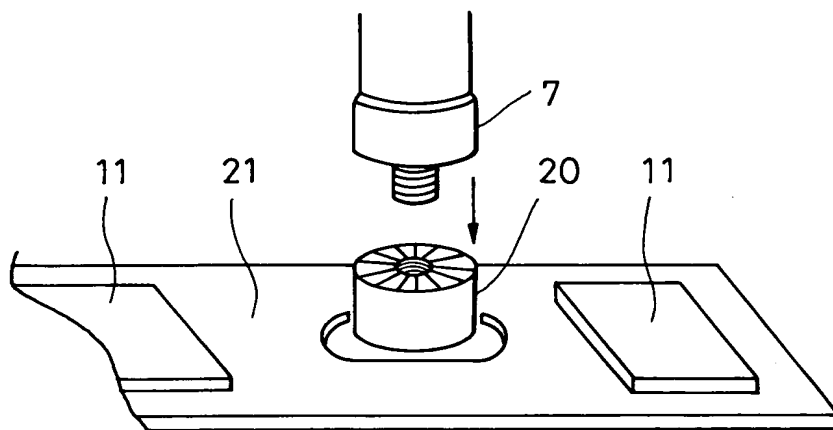


FIG. 5

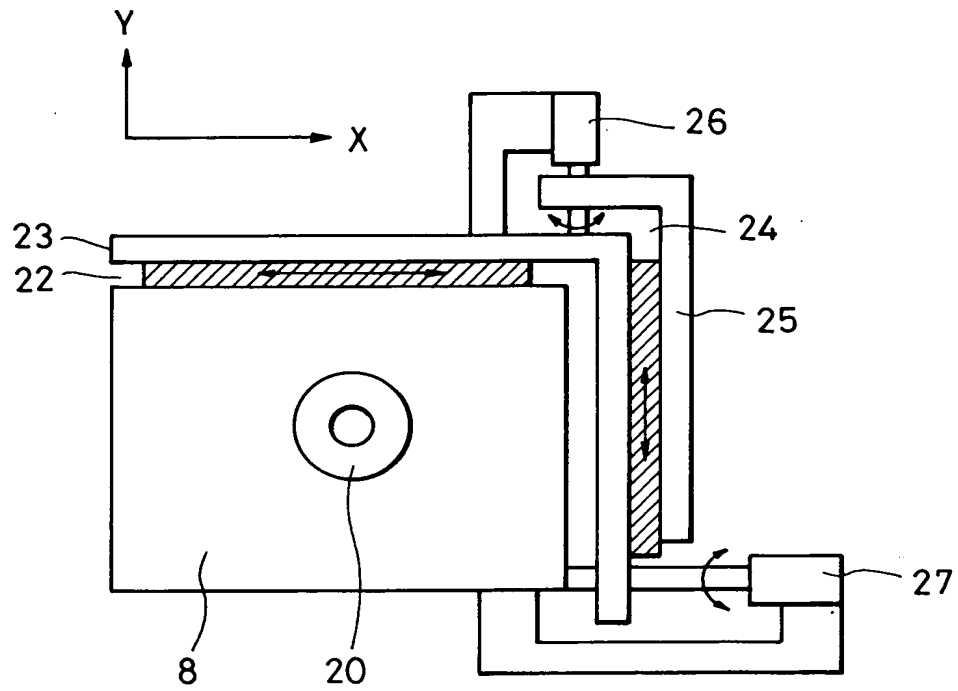
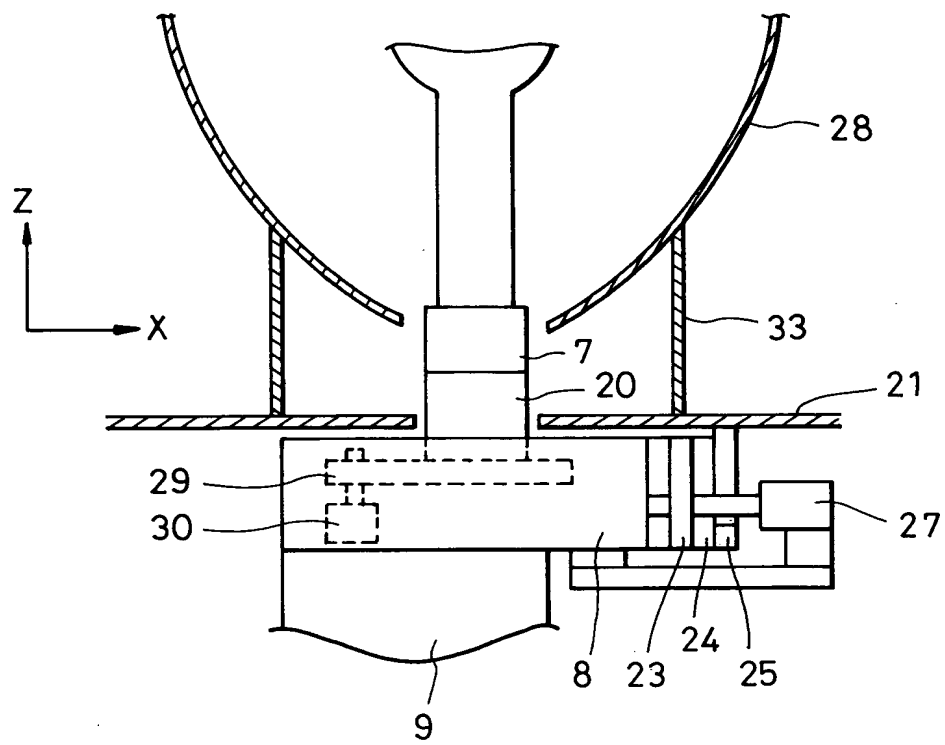


FIG. 6



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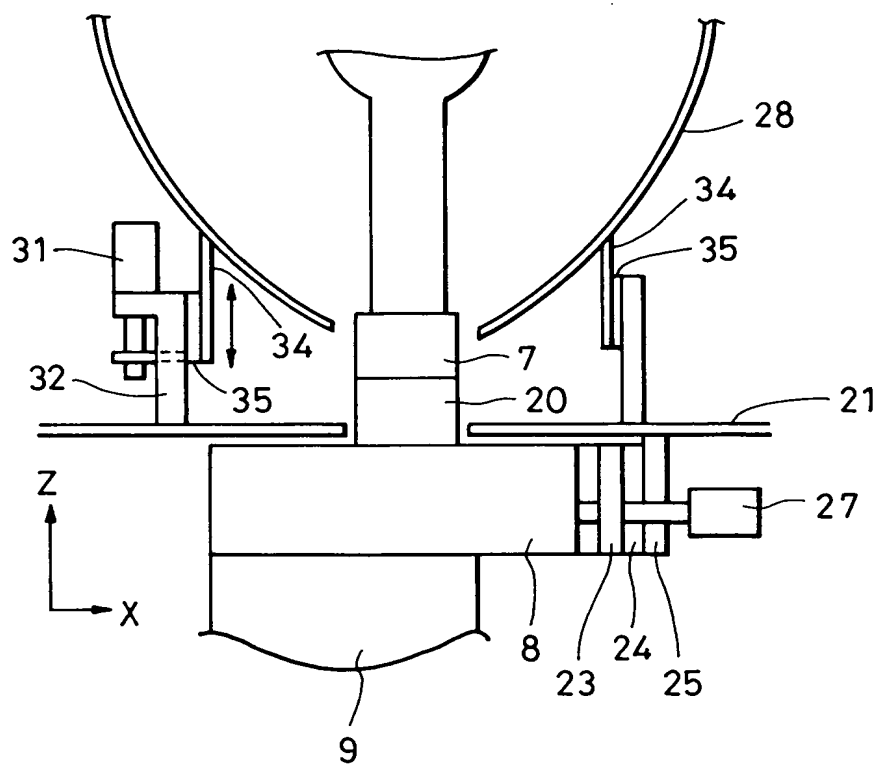
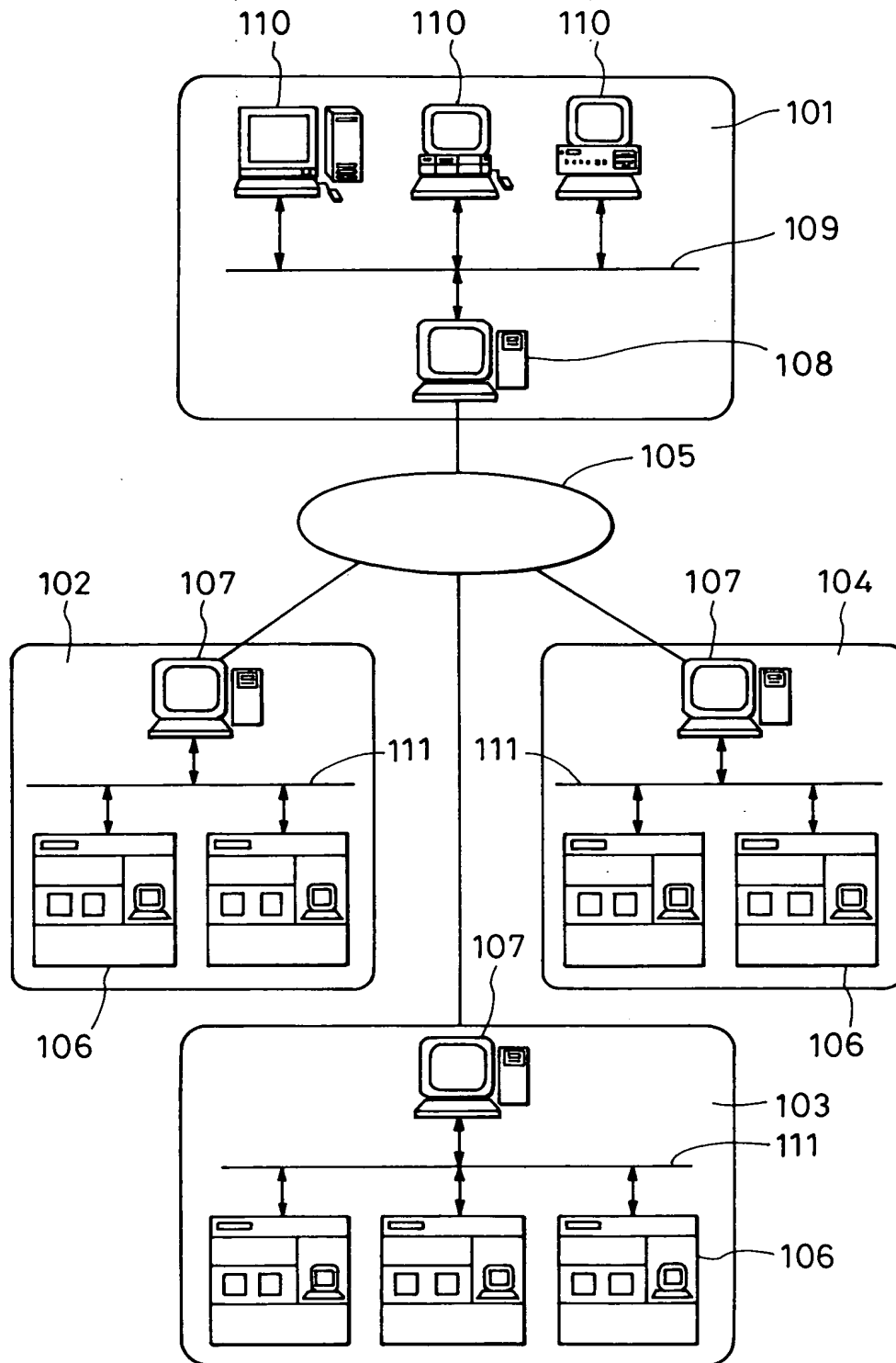
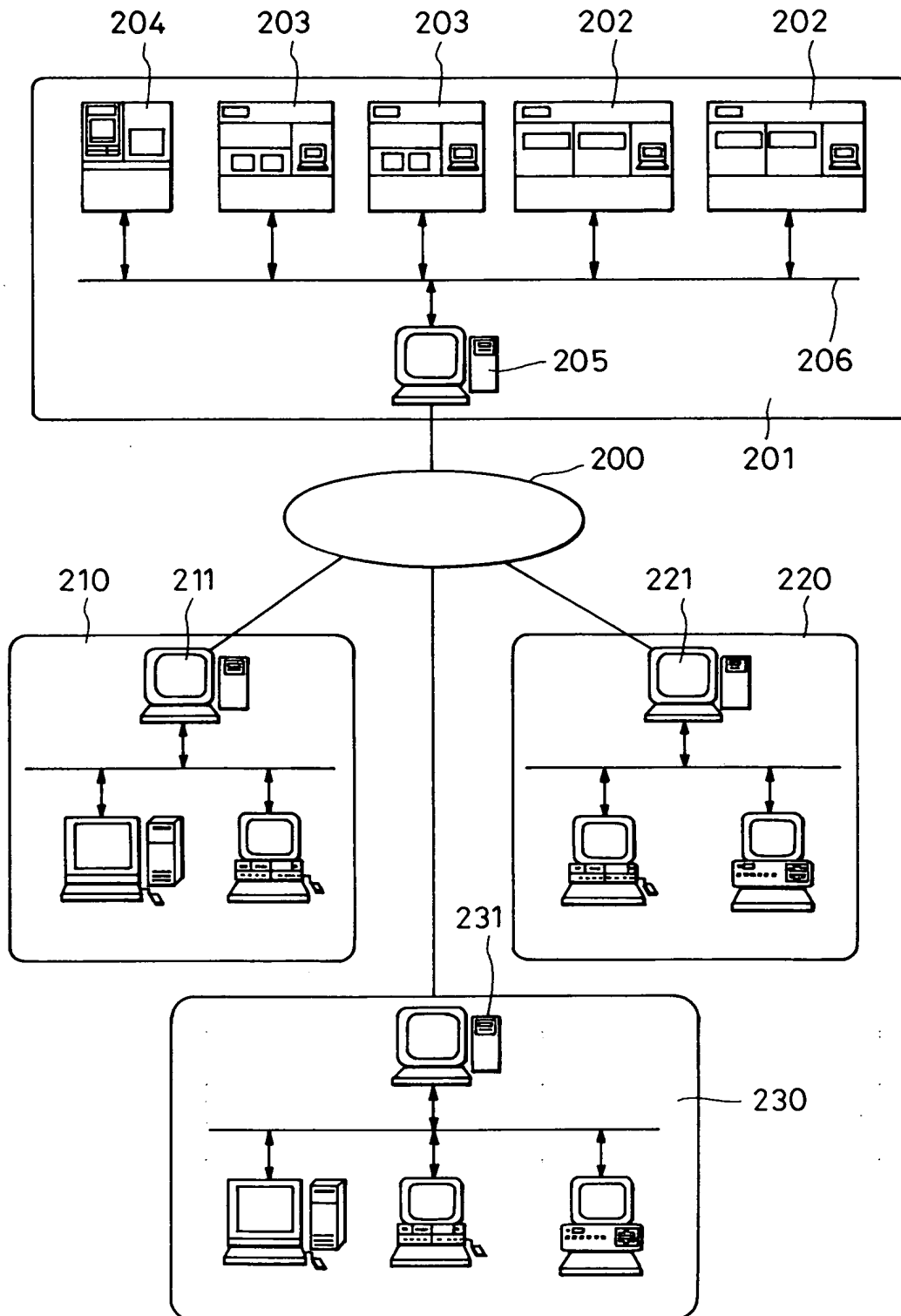


FIG. 8



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FIG. 9



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FIG. 10

URL

TROUBLE DATABASE INPUT SCREEN

DATA OF OCCURRENCE 404

MODEL 401

TITLE 403

EQUIPMENT SERIAL NO. 402

URGENCY 405

SYMPTOMS 406

MEASURES 407

RESULTS 408

410

[LINK TO DATABASE OF LIST OF RESULTS](#) 411

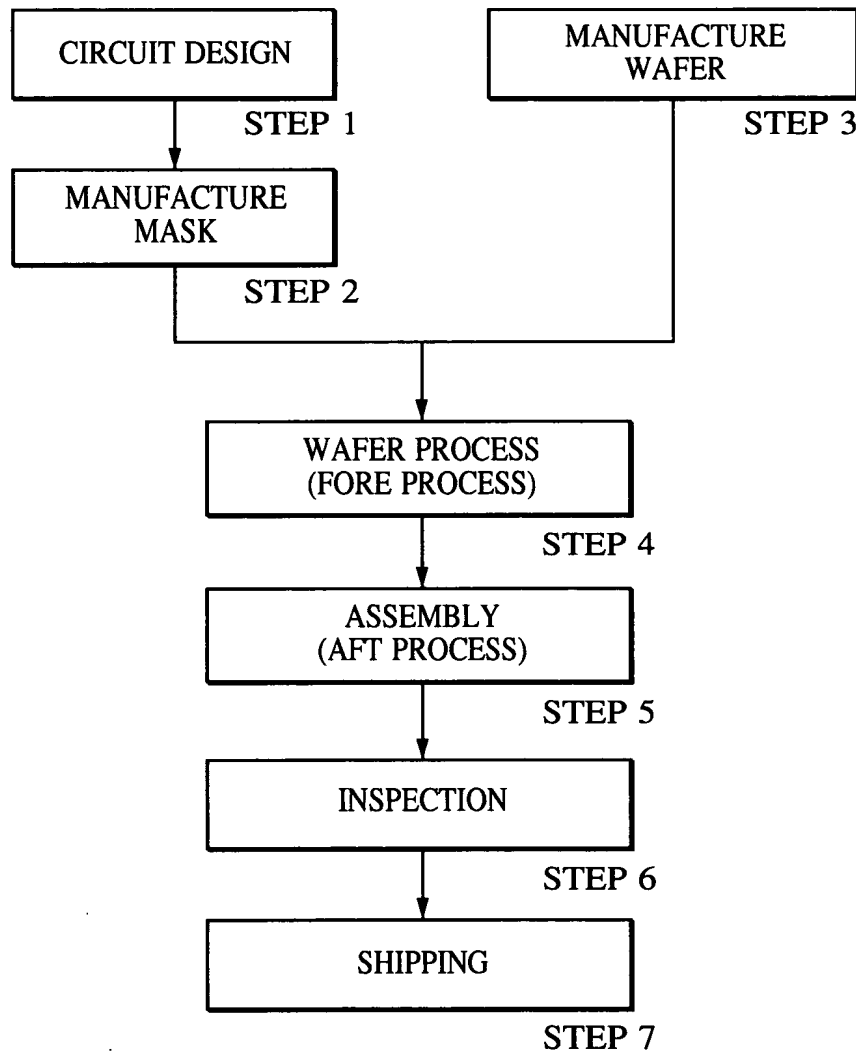
[SOFTWARE LIBRARY](#) 412

[OPERATING GUIDE](#)

20051027 22:44:00

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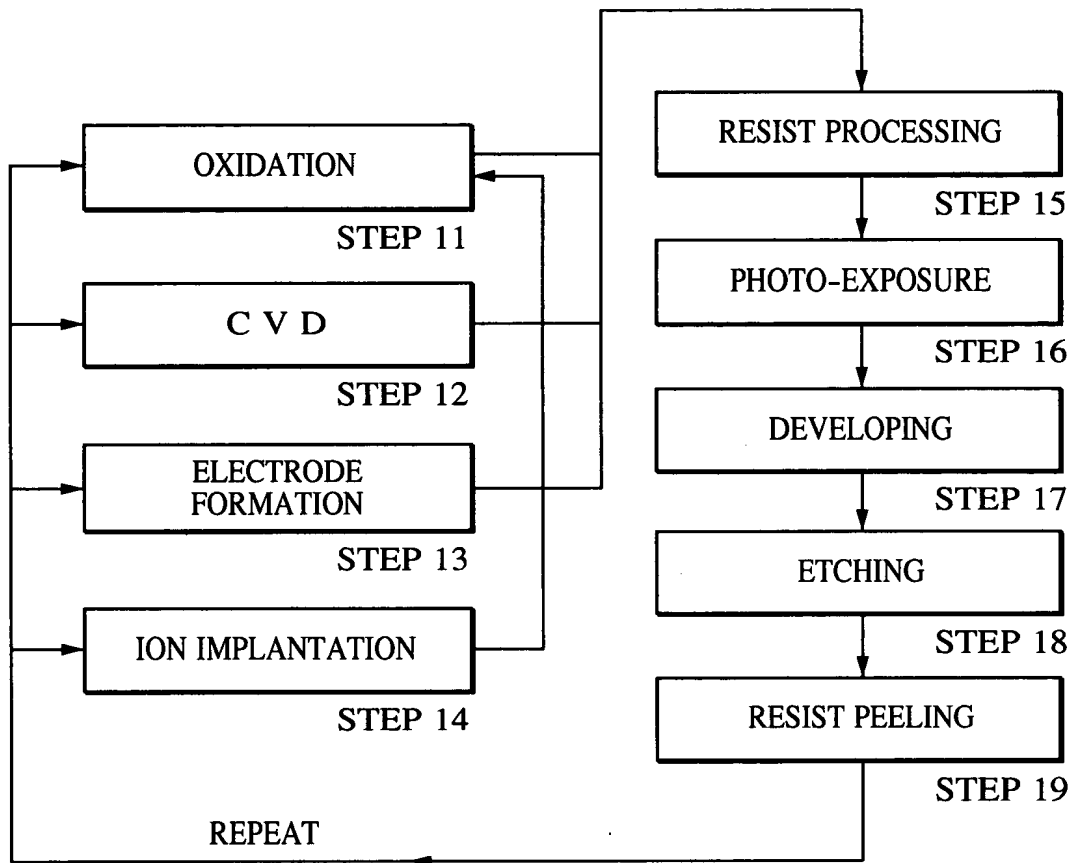
FIG. 11



FLOW FOR MANUFACTURING SEMICONDUCTOR DEVICES

205710" 26574007

FIG. 12



WAFER PROCESS